



IFW/AF

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **Mamoru NAKASUJI et al.**

Group Art Unit: **2881**

Serial No.: **10/766,041**

Examiner: **Phillip A. Johnston**

Filed: **January 29, 2004**

Confirmation No.: **2576**

For: **ELECTRON BEAM APPARATUS AND METHOD OF  
MANUFACTURING SEMICONDUCTOR DEVICE USING THE  
APPARATUS**

Attorney Docket Number: **011470A**

Customer Number: **38834**

**AMENDMENT AFTER FINAL REJECTION**

Mail Stop AF  
Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

Date: June 13, 2005

Sir:

This paper is filed in response to the Office Action dated April 5, 2005.

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 14 of this paper.